

GWADW 2015
May 17-22, 2015
Girdwood, Alaska



Coatings

Review talk on the status of the art and known limitations



Gianpietro Cagnoli

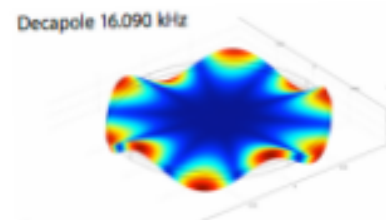
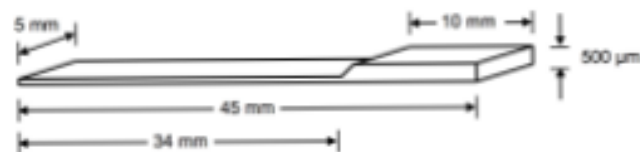
Laboratoire des Matériaux Avancés
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Université de Lyon
Villeurbanne (FR)



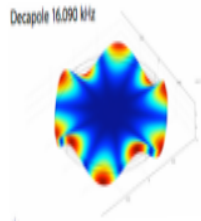
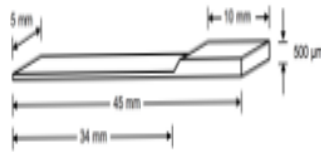
Methodologies

FROM S.PENN PRESENTATION ON MONDAY

- Mechanical loss measurements
 - Cryogenic Measurements on Cantilevers [Glasgow]
 - Room temperature measurements on thin disks [AU]
- Structural measurements
 - Bond length and element distribution: EXAFS; FEM; EELS, XRD, NMR [Stanford & Glasgow]
 - Elastic modulus measurements [Caltech & Glasgow]
- Direct Thermal Noise Measurements
 - Optical Cavities [Caltech & Florida]
 - Thermo-optic measurements [ERAU & Whitman]
- Theoretical Models [Florida]
 - Young's Modulus and loss approaching observed values.



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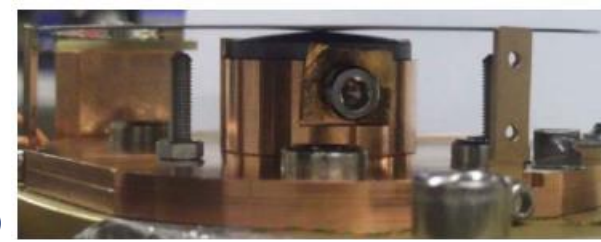
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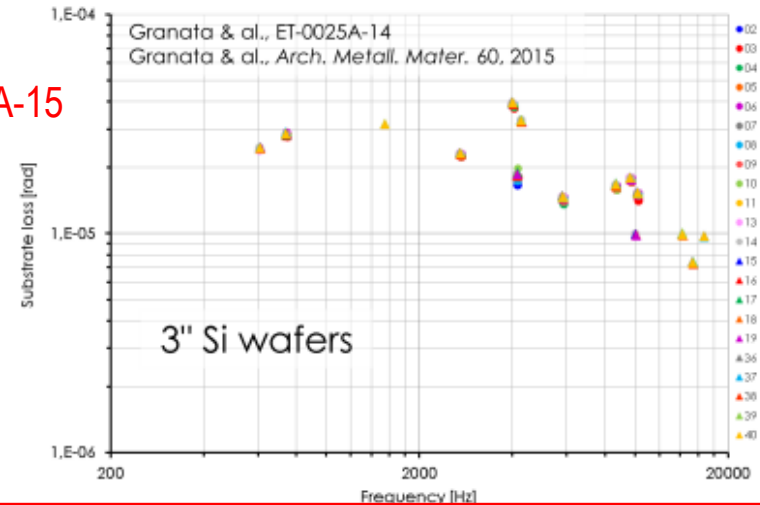
- Young's Modulus and loss approaching observed values.

LYON: LMA, ILM,
LPENS, INL

GeNS: room T
and cryo



VIR-0204A-15



- Raman, Brillouin [ILM]
- Elastic modulus measurement [LMA, INL]
- Measurement of thermal noise on μ -cantilevers, [10, 2e4] Hz [LMA, LPENS]

Granata, GWADW 2014

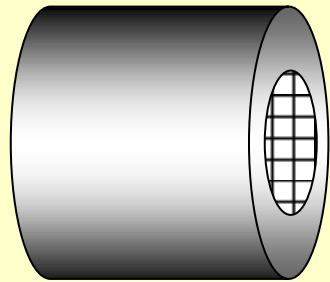
- Molecular dynamics [ILM]
identification of relaxation mechanisms

a-Silicon Coatings

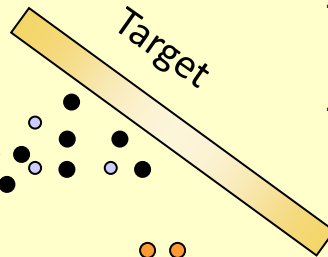
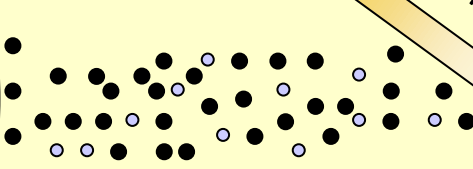
- From Liu [PRL 113, 025503 (2014)] *“A densely packed and near perfect tetrahedrally bonded amorphous system can be physically constructed without requiring H by growing a-Si at a higher T, which we suggest was the dominant reason for removing the TLSs in both a-Si and a-Si:H. ... Recent theoretical work suggests local regions of ϵ embedded in ϵ forming at the* This supports the suggestion made by Phillips 40 years ago, in which he speculated that TLSs may originate from an “open structure” with “low coordination” [5]. He argued that if every atom is linked to more than two neighbors (like in *a*-Si and *a*-Ge), the structure is overconstrained and double-well potentials are unlikely.

The deposition technique

Ion source



Ar⁺ ion beam



Electrons

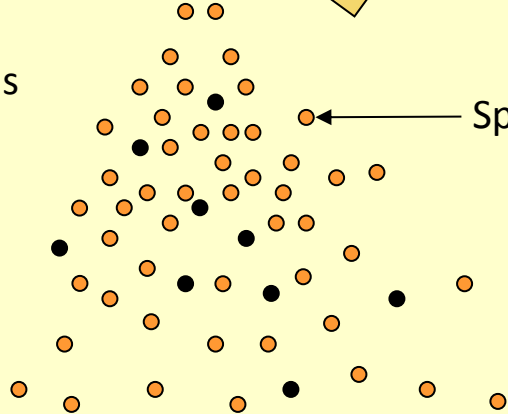


Neutralizer

- Ion Beam Sputtering

- Extremely low optical absorption
- Compact layers (low porosity)

Sputtered particles



Growing layer

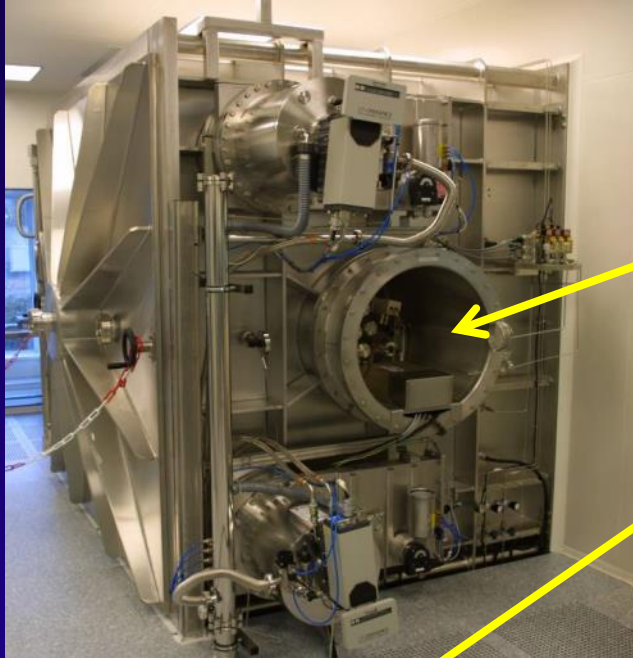
Substrate



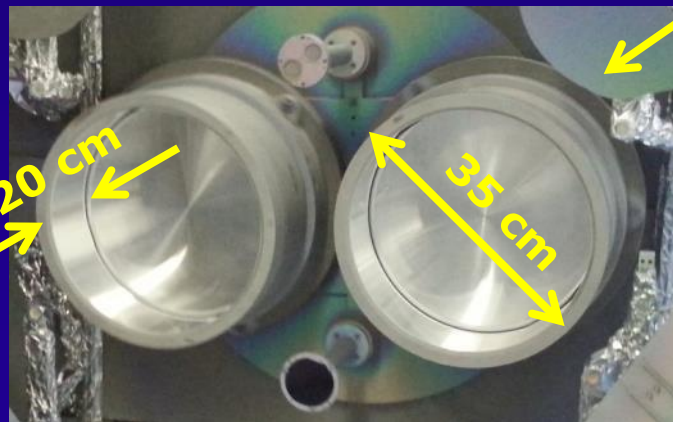
Quartz microbalance

Benoit Sassolas - LMA

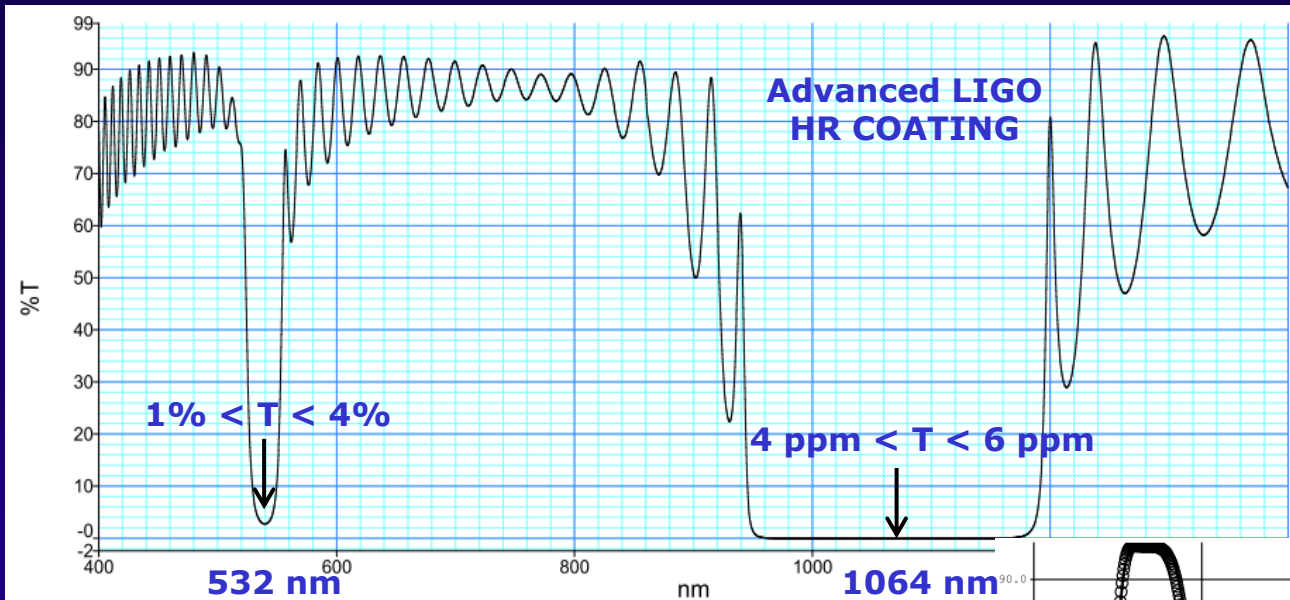
The coater



- Vacuum Chamber 2.4 x 2.4 x 2.2 m
- Pumping Units : 10^{-7} Torr in 1h
- RF Ion sources
- Max coating diameter ~ 1 m
- Clean Room class 1(ISO3)
- 2 mirrors at a time

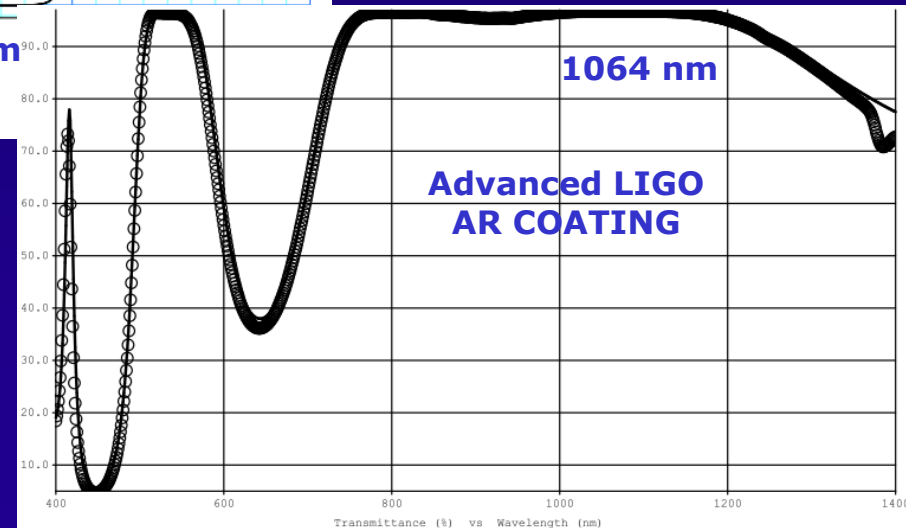


Transmission and Reflectivity

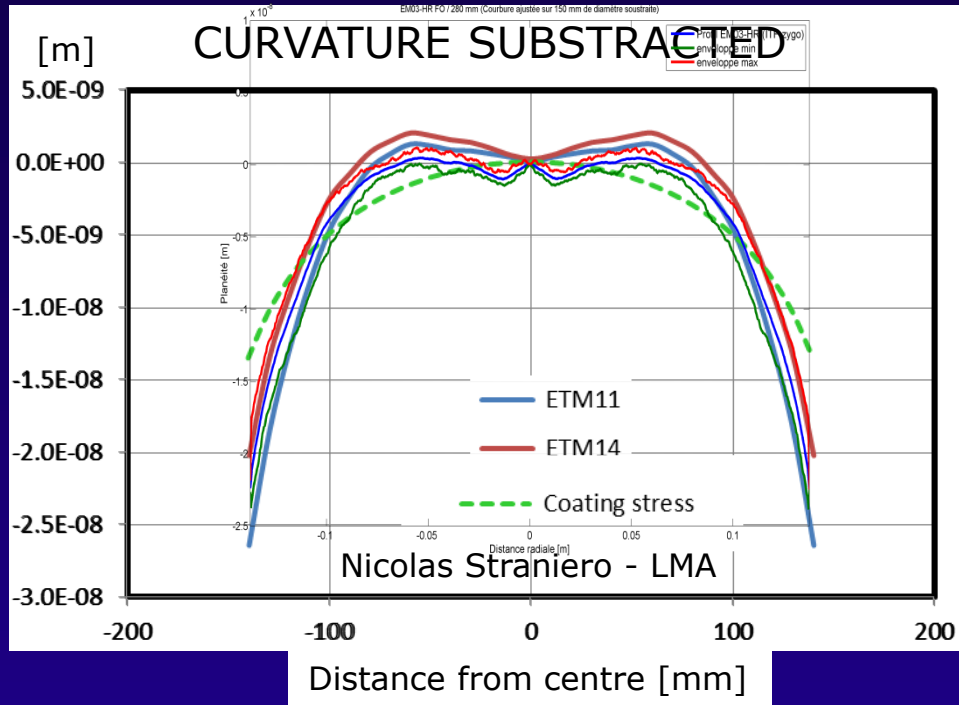


13 ppm < R < 54 ppm

Christophe Michel - LMA

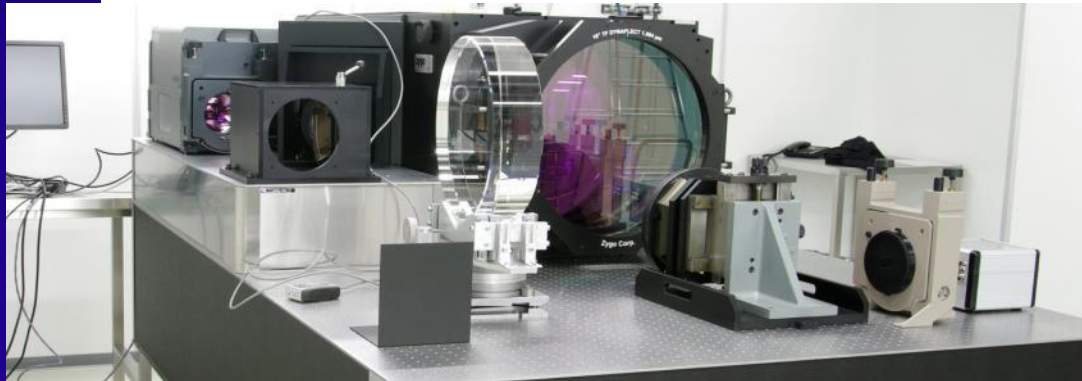


Coating uniformity



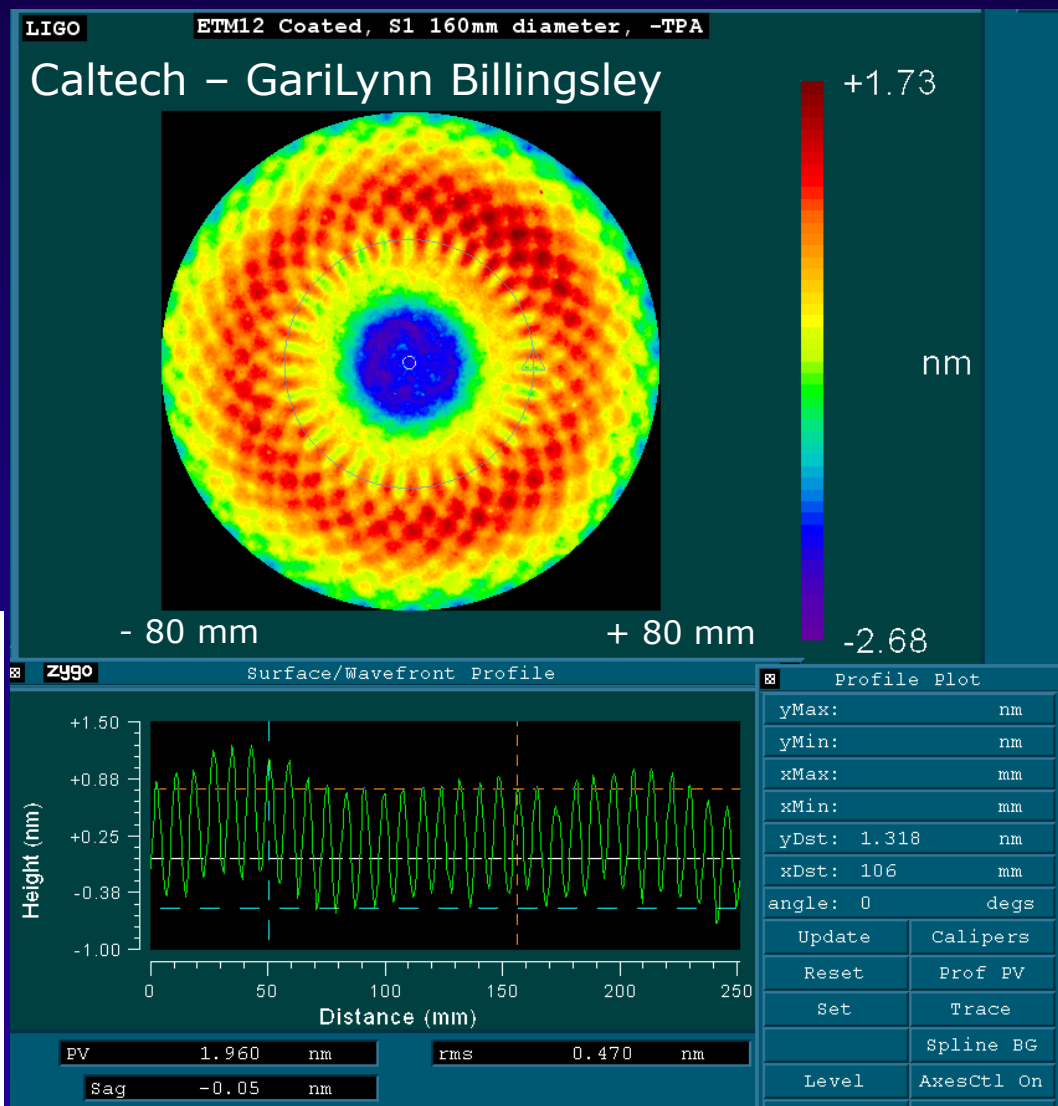
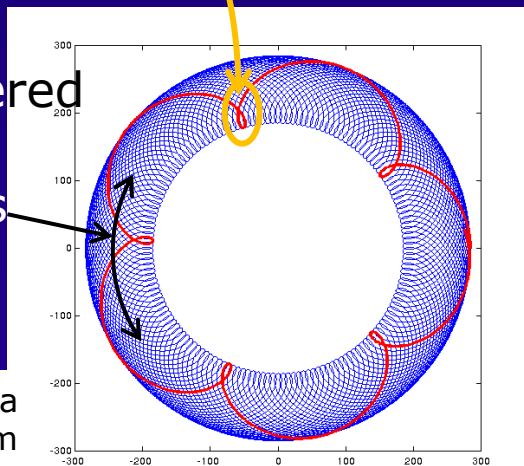
- Profile measured with a wavelength shifting 18" interferometer
- On 160 mm diameter we have a flatness of ~ 0.5 nm (power removed)
- Total coating thickness 6000 nm
- Compressive coating stress

18" WAVELENGTH SHIFTING ZYGO INTERFEROMETER



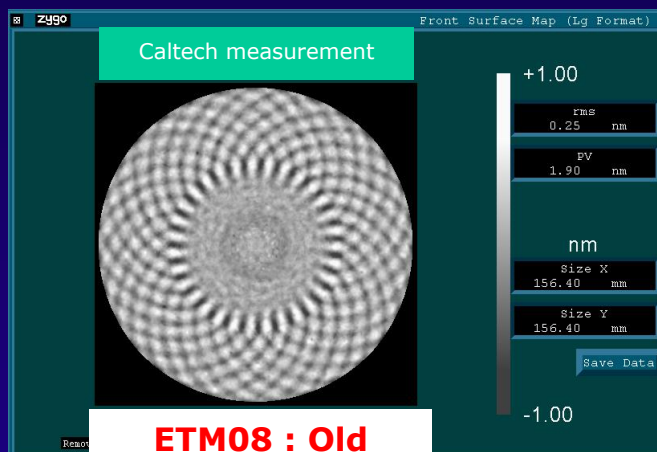
Origin of spirals

- Spiral = consequence of the combination of the planetary motion and the mask
- Amplitude max ~ 1.5 nm on the 40 mm radius circumference
- The part of the trajectory that is almost radial makes the total amount of deposited material sensitive to the gradient of sputtered material in this direction

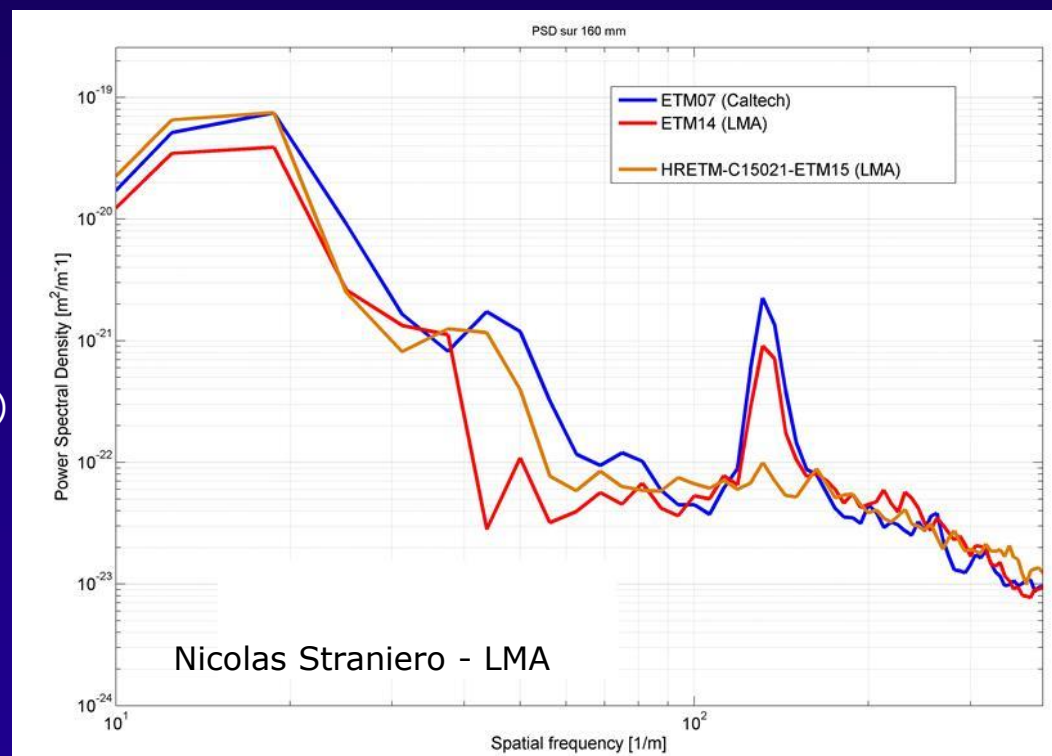
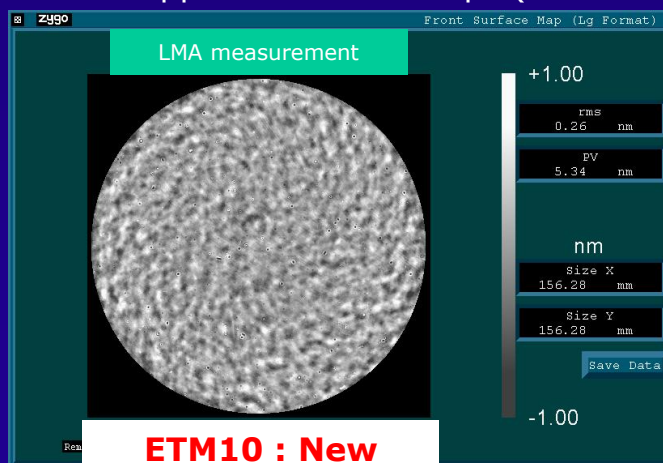


The solution

- Destructive interference between 2 spiral patterns shifted π one w.r.t. the other



High pass filter applied on the 2 maps (same scale)

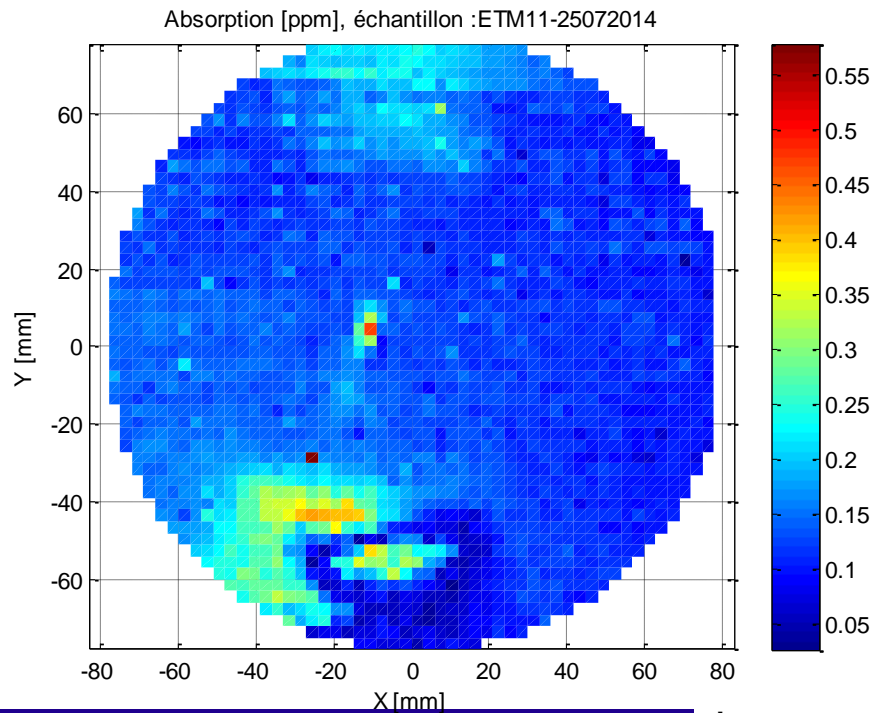


Laurent Pinard - LMA

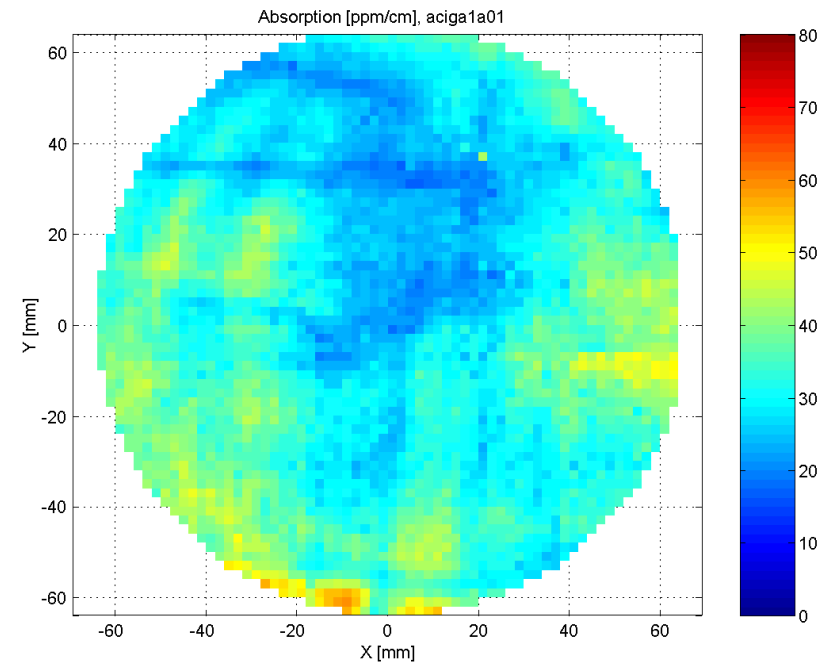
Absorption

- Absorption Map on aLIGO ETM HR coating
- (0.14 +/- 0.05) ppm
- Absorption map $\varnothing 150$ mm of a Sapphire substrate (2004)

Coating absorption



Bulk absorption

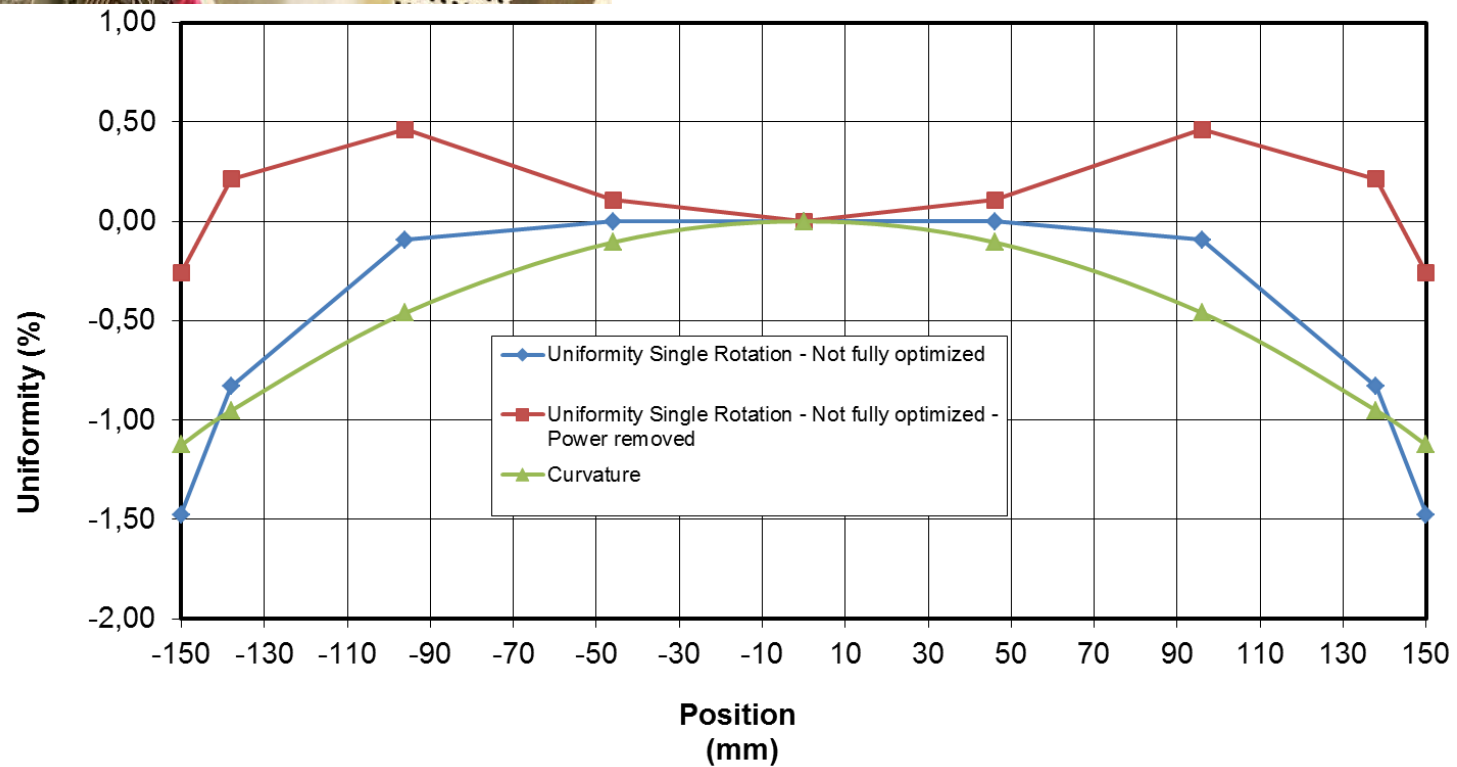
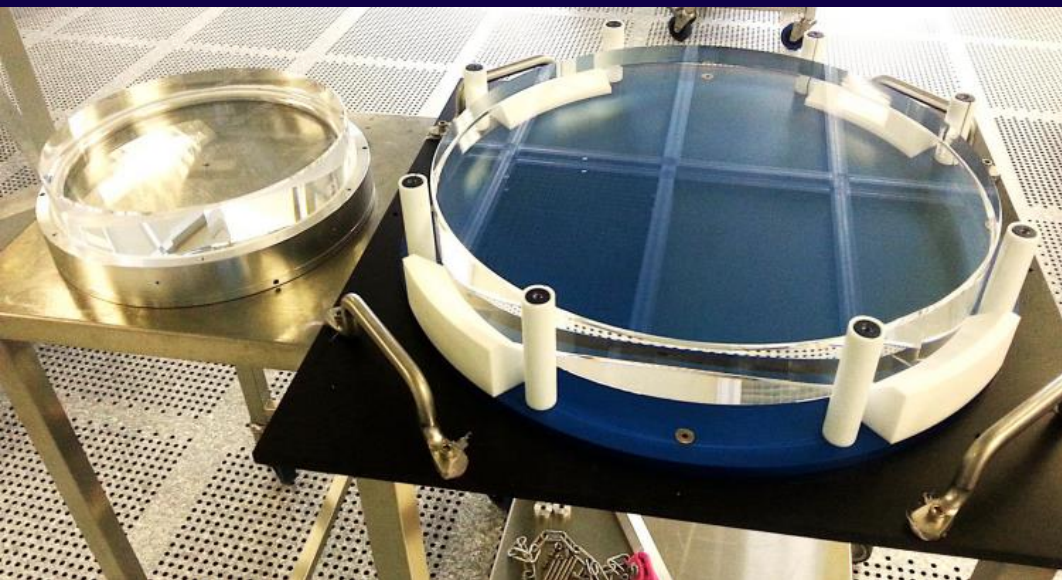


Laurent Pinard - LMA

The future of IBS

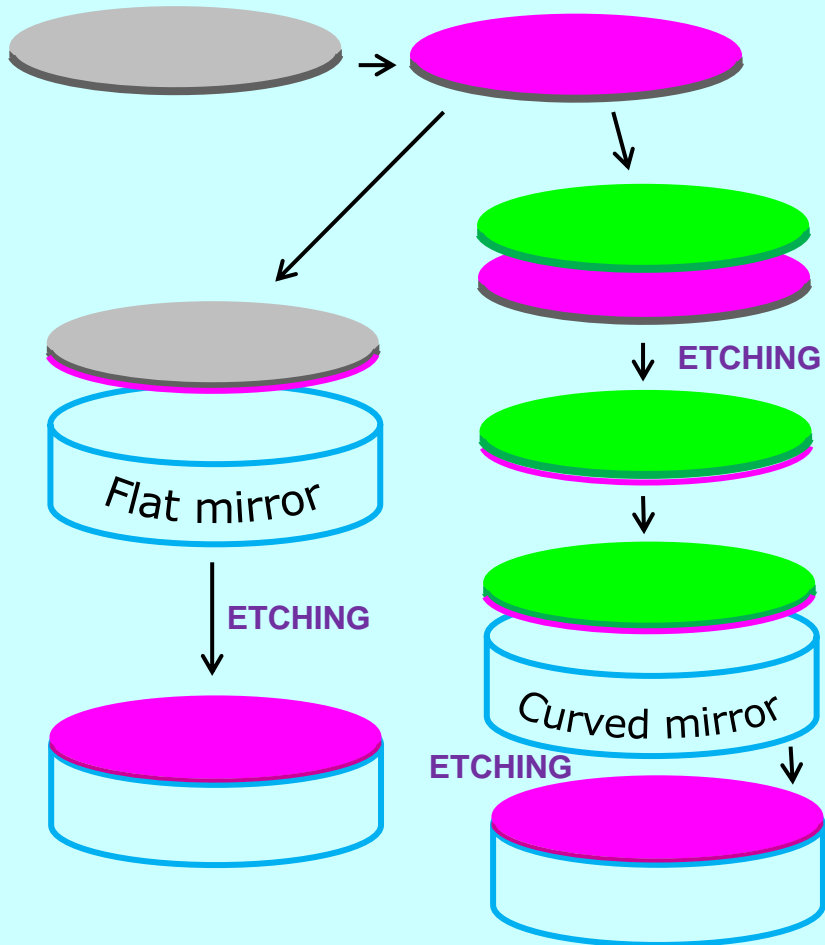
- Planetary motion (matched mirrors)
 - Optics with $\varnothing_{\max} = 40$ cm
 - Uniformity: < 0.5 nm rms on $\varnothing 30$ cm
 - Ready by 2016
- Single rotation (1 mirror at a time)
 - No masks, no planetary \rightarrow no spirals
 - $\varnothing_{\max} = 60$ cm, 200 kg substrate mass
 - Able to deposit nanolayers
 - Uniformity: < 0.5 nm rms on $\varnothing 40$ cm
 - In-situ optical control of coating thickness \rightarrow matching of transmission between different runs

The Virgo BS

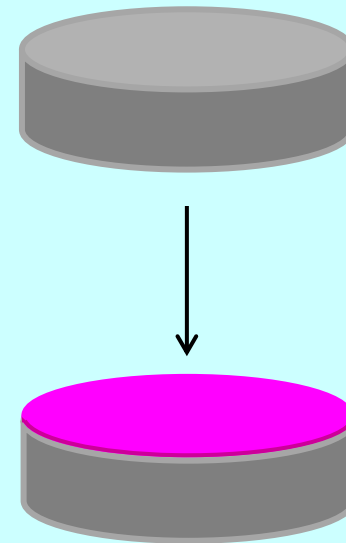


Cristalline coatings: the technologies

AlGaAs



AlGaP



Cristalline coatings: the issues

AlGaAs

- CONS
 - Wafer maximum dimension
 - Bonding on large surface
- PRO
 - Full stack achieved with good optical properties
 - Choice of the « good » side
 - Choice of substrate

AlGaP

- CONS
 - Full stack not achieved yet
 - One-chance growth
- PRO
 - Simplicity

- Thickness uniformity < 0.5 nm on Ø 40 cm
- Cryogenic operation
- Dedicated MBE